

Customer:

Product Change Notice (PCN Tracking Number: EE-QR-220409-20)

All Customers

Version: 1

KH000/F1, K1,	ET and CT serie	es, refer to <u>Pro</u>	auct List	<u> </u>
Addition of wa	afer type for N	aka products		
Wafer Process	Current wafer	specifications	Wafer	specifications after change
Naka	EPI \	Wafer		EPI Wafer Non-EPI Wafer
addition of non-	EPI wafers for N	Naka products		
Identifiable by T	T/C code on mar	king and label	for each	product.
				ds sequentially
Fit: Form: Function: Quality & Reliab	oility:	No change No change No change No change		
EEQC-PCN-CR	R-22-0090			
AMBD-2022-03	51, AMBD-2022	2-0428		
contact:				
E	E-mail			PHONE No.
gineer F	arhad.Banihash	nemi@renesas	s.com	+49-211-6503-1844
<b>mail, fax or mai</b> l Con	npany:			
Phone / Fa	ax No.:			
ement is provided o make any obje	d by Customer, to the PC	then Customer  N. If Customer  consider the F	r shall ha r fails to PCN cha	ave 90 days from the date make objections to this
		rith a last time	buy dem	
		rith a last time	buy dem	nand and purchase order.
	Addition of water Process  Naka  In order to realize addition of non-are current wafer lighter	Addition of wafer type for N  Wafer Process Current wafer  Naka EPI V  In order to realize stable supply addition of non-EPI wafers for N are current wafer specifications Identifiable by T/C code on mark Requested approval Change implementation  Fit: Form: Function: Quality & Reliability:  EEQC-PCN-CR-22-0090  AMBD-2022-0351, AMBD-2022  contact:  E-mail gineer Farhad.Banihash  company:	Addition of wafer type for Naka products    Wafer Process   Current wafer specifications	In order to realize stable supply, Renesas will impleme addition of non-EPI wafers for Naka products in additionare current wafer specifications in Naka.  Identifiable by T/C code on marking and label for each Requested approval 15. Jul. 2022 Change implementation from Jul. 2022 onward Fit: No change Form: No change Form: No change Function: No change Function: No change Quality & Reliability: No change EEQC-PCN-CR-22-0090  AMBD-2022-0351, AMBD-2022-0428  contact:    E-mail gineer   Farhad.Banihashemi@renesas.com



### **Details of Change:**

Renesas has been faced with serious supply shortage of Si-wafers due to the demand increase for semiconductors in these years.

In order to avoid delivery shortage and to realize stable supply of Renesas' RH850 series we plan to add non-EPI wafers for the Si-wafer specifications of Naka products in addition to current EPI wafers.

Please refer to below summary for changed items:

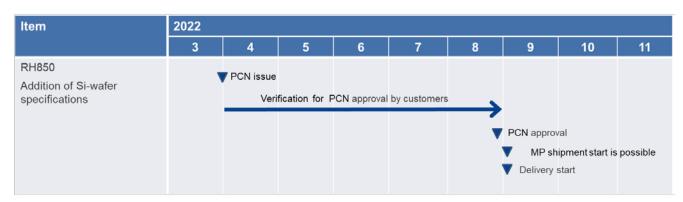
Wafer Process Site: Renesas Semiconductor Manufacturing Co., Ltd. Naka Factory

	Items	Current products	Changed products	Changes
1	Si-Wafer specifications	EPI Wafer	EPI Wafer non-EPI Wafer	w/

4 M1E change items	Conventional products	Change products	4M1E change items	Remarks
Man	Certified workers	<b>←</b>	No	
Machine	Machine A	<b>←</b>	No	
Material	EPI Wafer	EPI Wafer non-EPI Wafer	YES	Addition of Si-wafer specifications
Method	Process method A	<b>←</b>	No	
Environment	Process A	<b>←</b>	No	

Item	Judgement
Product names	No change
Marking	No change
Label	No change
Product identification	Controlled through Trace Code (T/C) described on Marking (Mark) and Label

# Schedule of Change:





# **Evaluation of the Change**

All potential risk items about addition of Si-wafer specifications were verified based on DRBFM. As a result, no problem has been confirmed.

Change Items	Impact due to changes	Concern items	Counter measures	Verification Methods	Judgment (Reference Section)
		Yield drop	Wafer-Test result confirmation	There is no yield difference between before and after change.	ок
		Yield drop	Final-Test result confirmation	There is no yield difference between before and after change.	ок
		Wafer-Test result confirmation	There is no yield difference between before and after change. There is no anomalous defect occurrence.	ок	
	Deterioration in characteristics	Final-Test result confirmation	There is no yield difference between before and after change. There is no anomalous defect occurrence.	ок	
			ED (Electrical Distribution) confirmation	There is no significant difference between before and after change.	ок
			Electrical characteristics	There is no significant difference in electrical characteristics between before and after change.	ок
	Impact on reliability	Deterioration in reliability	ESD characteristics	There is no significant difference between before and after change.	ок
			TEG reliability verification	Confirmation of process reliability.	ОК

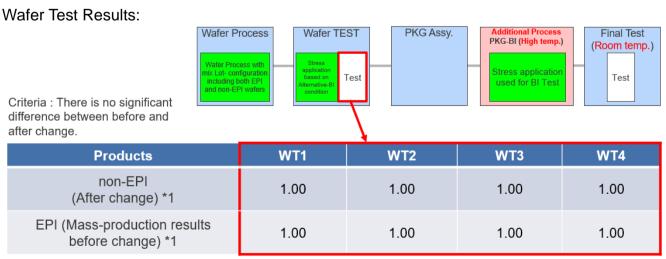
#### **Evaluation Results:**

To evaluate the additional wafer type the wafer process for RH850/F1L at Naka was performed with the identical lot which includes both non-EPI wafers and EPI wafers at the normal production flow.

Regarding representative products, we chose the RH850/F1L series whose test yield has been monitored at Naka. Packaged samples of the non-EPI wafers and EPI wafers were assembled at the mass-production flow of RSC.

Regarding stress-application Process, we performed PKG-BI Process in addition to Wafer Test under mass-production flows.

The conditions of used Wafer-Test programs, Final-Test programs, Tester and Test boards were the same as mass-production.

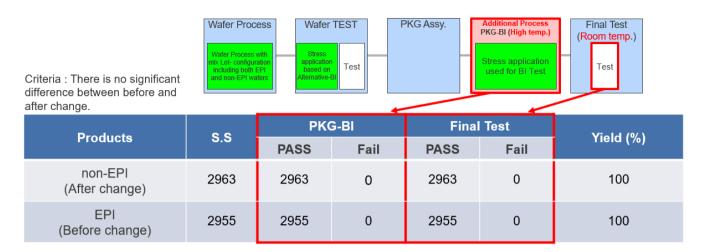


\*1 Relative values at EPI yield results (Mass-production results before change) = 1

We confirmed that there was no change in yield due to the change of Si-wafer specifications.



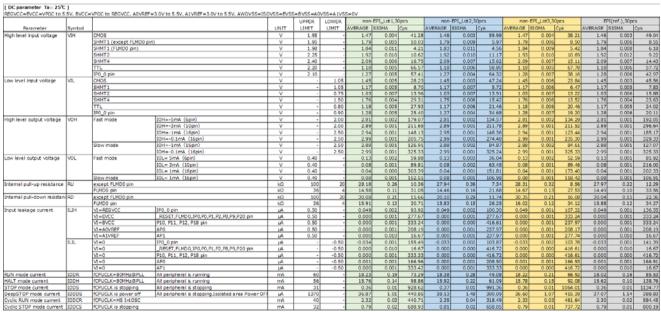
#### Final Test Results:



We confirmed that there was no yield drop due to change of wafer specifications and there was no significant difference between before and after change. We confirmed that initial defect samples of non-EPI wafers were sufficiently able to be rejected at the same stress condition as Epi wafers in Wafer Test.

# **Electrical Distribution Results:**

We confirmed the electrical distribution results at 4 temperatures (-40°C, +25°C, +105°C, +125°C) and confirmed no significant difference between non-EPI and EPI products. Cpk for all parameters is > 1.67.

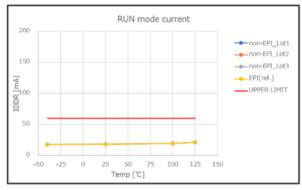


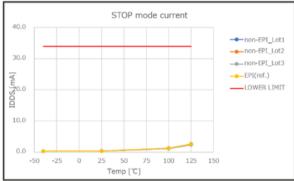
Example of electrical distribution at +25°C

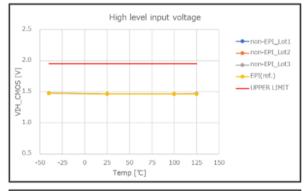


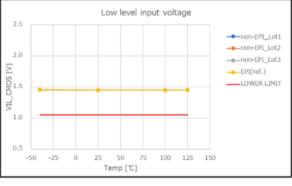
# **Electrical Characteristics:**

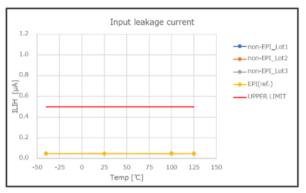
We confirmed that there was no significant difference in electrical characteristics between EPI and non-EPI products.

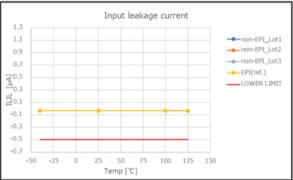


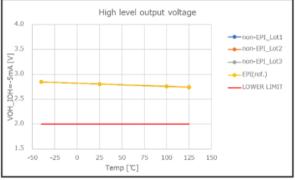


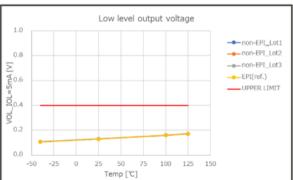












◆Products: RH850/F1L-2M ◆PKG: 176pin QFP ◆ASSY: RS



### **Reliability Evaluation Results:**

#### ESD and LATCH-UP results:

The following table shows ESD/LATCH-UP Test results for EPI/non-EPI wafers. The results of ESD and LATCH-UP Test between wafer specifications were equivalent and there were no problems.

Test type	Target specification	Number of sample	EPI wfr. of N3	non-EPI wfr. of N3
НВМ	AEC-Q100 +/- 2000V	3pcs	ОК	ок
CDM	AEC-Q100 +/- 500V (All pin)	3pcs	ОК	ок
Latch-up	AEC-Q100 +/- 100mA	6pcs	ОК	ок

# Reliability impact confirmation:

We completed TEG evaluation about extracted concern items based on addition of Si-wafer specifications.

We confirmed that non-Epi products were equivalent to Epi products in all items through TEG evaluation.

Change items	Change points	Concern items	Confirmation items	Confirmation results (EPI <-> non-EPI difference)
due to addition of impurities and precipitates		Change in reliability (Breakdown-voltage	TDDB	We confirmed that there was no significant difference.
Si-Wafer in crystals and deterioration specifications (EPI -> non-EPI) to decrease in BMD*1 density	characteristics) of Gate-Oxide films	TZDB	We confirmed that there was no significant difference.	
	Changes in reliability (Retention	HCI	We confirmed that there was no significant difference.	
	characteristics) of Tunnel-Oxide films	NBTI	We confirmed that there was no significant difference.	
			SILC/TDDB	We confirmed that there was no significant difference.

<sup>\*1</sup> Bulk Micro Defects: Crystal defects due to Oxygen precipitation



# **Product List**

R7F7010023AFP#AA4
R7F7010023AFP#BA4
R7F7010023AFP#KA4
R7F7010033AFP#AA2
R7F7010033AFP#BA2
R7F7010033AFP-C#AA2
R7F7010073AFP#AA4
R7F7010073AFP#BA4
R7F7010073AFP#KA4
R7F7010074AFP#AA4
R7F7010104AFP#AA4
R7F7010114AFP#AA4
R7F7010114AFP#KA4
R7F7010124AFP#KA4
R7F7010133AFP#AA4
R7F7010133AFP#BA4
R7F7010133AFP#KA4
R7F7010134AFP#AA4
R7F7010134AFP#BA4
R7F7010134AFP#KA4
R7F7010143AFP#AA2
R7F7010143AFP#BA2
R7F7010153AFP#AA2
R7F7010153AFP#BA2
R7F7010153AFP#KA2
R7F7010154AFP-C#AA2
R7F7010163AFP#AA4
R7F7010174AFP#KA4
R7F7010183AFP#AA4
R7F7010183AFP#BA4
R7F7010184AFP#AA4

R7F7010184AFP#KA4
R7F7010214AFP#KA4
R7F7010223AFP#AA4
R7F7010233AFP#AA4
R7F7010233AFP#BA4
R7F7010233AFP#KA4
R7F7010234AFP#AA4
R7F7010243AFP#AA2
R7F7010243AFP#BA2
R7F7010243AFP#KA2
R7F7010253AFP#AA2
R7F7010254AFP#AA2
R7F7010283AFP#KA4
R7F7010304AFP#AA4
R7F7010304AFP#BA4
R7F7010323AFE#KA4
R7F7010323AFP#AA4
R7F7010323AFP#BA4
R7F7010323AFP#KA4
R7F7010323AFP-C#KA4
R7F7010413AFP#AA2
R7F7010413AFP#BA2
R7F7010414AFP#AA2
R7F7010434AFP#AA2
R7F7010443AFP#AA2
R7F7010453AFP#AA2
R7F7010454AFP#AA2
R7F7010573AFP#AA4
R7F7010574AFP#AA4
R7F7015013AFP#AA1
R7F7015693AFP#AA1